WYKO NT 1100 Optical Profilometer

DESCRIPTION:

- For applications in MEMS, thick films, optics, ceramics and other advanced materials
- Utilizes white light interferometry
- 3D surface measurements, from sub-nanometer roughness to millimeter- high steps
- Vertical Measurement Range: 0.1nm to 1mm
- Vertical Resolution: < 1Å Ra
- RMS Repeatability: 0.01 nm
- Vertical Scan Speed up to 7.2µm/sec (288µin./sec)
- Lateral Spatial Sampling 0.08 to 13.1µm
- Field- of -View: 8.24mm to 0.05mm (larger areas with Data Stitching option)
- Reflectivity: 1% to 100%

LOCATION: ANALYTICAL DIAGNOSTICS LABORATORY

CONTACT US

IEEC

BINGHAMTON UNIVERSITY

CONTACTS

For more information or to arrange for the use of this equipment, contact any of the IEEC staff members listed below:

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